Preparation of TiO₂ thin films by using aerosol flame depositon process

<u>Ding Jinrui</u>, 김동주, 김교선* 강원대학교 (kkyoseon@kangwon.ac.kr*)

The aerosol flame deposition (AFD) process is capable of preparing nano-sized metal oxide films from liquid precursors. In our study, We prepared titania thin films with the titanium tetra-isopropoxide (TTIP) precursor by using AFD process. The flame torch was moved zig-zag in an x and y directions for uniform deposition of the thin films. TTIP was carried into the central tube of the torch by flowing N_2 gas, and TiO₂ was formed by oxy-methane flame and deposited on a substrate placed in a cooler holder.